

Motic®

PSM-1000

Laser Ready Modular Microscope



PSM-1000 Features

Ergonomic Design

The design of the PSM-1000 encourages the optimal amount of usability without sacrificing comfort.

Ergonomically constructed for all major forms of image adjustment to be accessible within the span of your hand.

- ① Diopter
- ② Aperture Diaphragm
- ③ Beam Splitter
- ④ Changeover Turret
- ⑤ Analyser/Polariser



Laser Work¹

The PSM-1000 is standard equipped for laser work covering the spectrum ranging from 355nm [UV] to 532nm [Green] to 1064nm [IR]. Conveniently positioned, the beam splitter switches the PSM-1000 from a visual unit [50:50 split between binocular eyetubes and trinocular port] to a laser work unit. Through the specially coated optical system, the PSM-1000 produces an infrared [1064nm] efficiency of **82%²**.

Central to the PSM-1000's high laser efficiency and functionality is the changeover turret, which consists of three specialised lenses. 1XUV/VIS for the spectrum of 355nm - 532nm; 1XIR/VIS for the 532nm - 1064nm spectrum; and a 2XVIS magnifier to achieve optimal magnification of 2000X [with 100X objective]. The turret base design provides the convenience of rapid switching between spectrums to complete the task.

With safety in mind, the PSM-1000 includes a laser safety pin to shut down the laser to avoid accidents, as well as shims to securely mount and hold the laser provider's safety filter.



Focusing Block

Rated for load weights up to 45lbs., image focal planes can be adjusted at 1µm resolutions within the total 50mm stroke. Reversible for space conscious applications in addition to extra mounting slots for placement on other manufacturers' microscopes, adaptability is the key with the PSM-1000 focusing block.



Adjustable Nosepiece

Forward facing and equipped for four M26 x 1/36" (0.706) type objectives, the PSM-1000's nosepiece is dovetail mounted for moulding to different types of research and usage. Complementing the versatility of the nosepiece is Motic's hassle-free parcentration. With the standard centering keys [pictured on the right], parcentration of individual ports can be achieved while remaining focused on the sample.



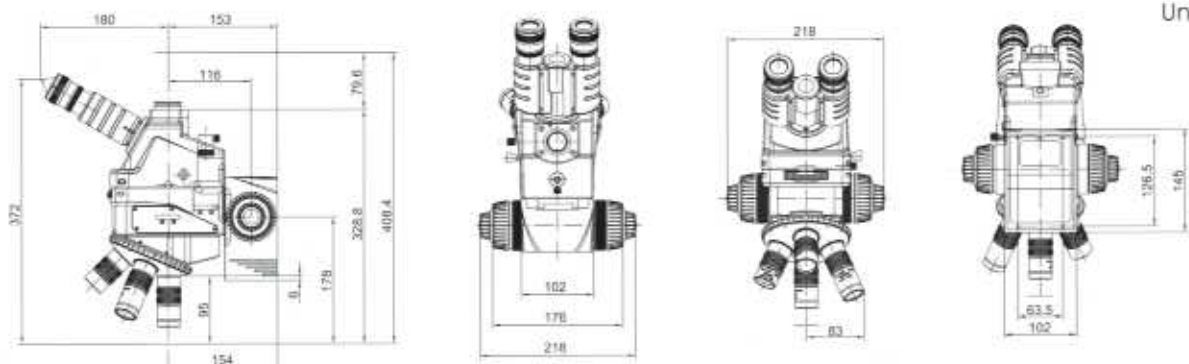
1. Motic assumes no responsibility whatsoever for the performance and/or safety of the laser system used with the Motic PSM-1000 microscope. See laser manufacturer for proper operation.
2. Tested by New Wave Research (Fremont, California, USA). For detailed information, contact your local Motic supplier.

SPECIFICATION OF LASER READY MODULAR MICROSCOPE PSM-1000

Purpose	Quick and Surface Inspection, Quality Control, Laser Repairs and Device Research
Observation Tube	Widefield trinocular tube, 50 : 50 and 0 : 100 optical observation angle Siedentopf infinity, 55 - 70mm Interpupillary distance
Eyepiece	Widefield High-eyepoint, Infinity Corrected 10x/24mm Accepts Ø25mm reticules
Turret	3-lens changeover turret 1x IR tube lens, 1x UV tube lens, 2x Visible magnifier
Laser Work	Pull out beam splitter, Laser Safety Pin, Shims
Wavelengths Coverage*	355nm [UV] to 532nm [Green] to 1064nm [IR]
Nosepiece	Quadruple, outward-facing Spring-loaded, Adjustable parcentration Dovetail mounted for easy removal
Objectives (Optional)	Extra and Ultra Long Working Distance Plan Achromat objectives Range of magnifications from 2x to 100x, M26 x 1/36" (0.706) thread size Adjustable parfocality available
Microscope Magnification Range	20x - 2000x
Aperture Diaphragm	Adjustable field of depth and contrast, Adjustment range : Ø0.8 - Ø6mm
Focusing Block	50mm Stroke Coaxial operation system Coarse 4mm per rotation Fine 0.1mm per rotation 1 µm resolution 45 lbs. Mountable weight
Illumination	Reflective illumination for brightfield
Optional Contrast	Polarisation Spectrum range: 400nm - 700nm Adjustable Polariser available
Fiber Optic Illumination (Optional)	Switchable power input [115V - 220V] 150W / 21V output 1,600,000 lux Colour Temperature Range: 500K - 3700K Flexible light guide with Ø15mm distal end
Weight [Head only]	16lbs.
Dimensions	372mm (h) x 218mm (w) x 333mm (d) - with focusing block

* Designed around the New Wave Research line of lasers

PSM-1000 DIMENSIONS

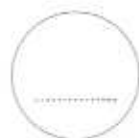


Eyepieces

Employing adjustable, high-eyepoint, Widefield 10x/24mm eyepieces, the PSM-1000 ensures the optimal amount of visual inspection. Each eyepiece can have diopter adjustments of $\pm 5^\circ$. An additional versatility is the acceptance of reticules [$\varnothing 25\text{mm}$].



Reticule
360° : 10°
SG060314



Reticule
14mm : 0.2mm
SG060320



Reticule
14mm : 0.1mm
SG060315



Plain Cross
Hair Reticule
SG060342



WF15x and 20x eyepieces

Plan Apochromat Objectives

Motic's Plan Apochromat objectives provide the working distances at the numerical aperture values needed. Covering magnification ranges from 2x to 100x, the Plan Apochromat objectives are also available with the unique option of parfocality adjustment. The mounting thread is M26 x 1/36" (0.706) for integration to existing systems. Please refer to Motic's Plan Apochromat catalogue for further information.



Digitalisation

Utilising a Moticam digital application camera with the corresponding optional camera adapters, the PSM-1000 becomes an analysing, documentation, teaching, and training system.



0.3x
Camera Adapter
[1/3" chip sensors]



0.4x
Camera Adapter
[1/2" chip sensors]



0.5x
Camera Adapter
[2/3" chip sensors]



1x
Camera Adapter
[1" and 2/3" chip sensors]



PSM-1000 with Moticam 3000 attached

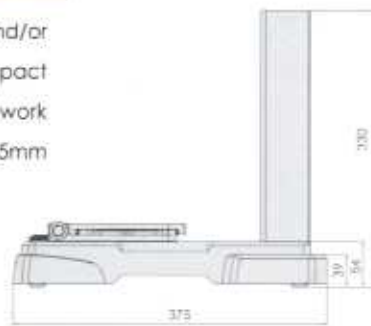
Tilting Head

With 300mm wafer fabrications coming online in addition to ergonomic requests, the PSM-1000 is offered with an optional tilting head format. The tilting head has an observation angle adjustment of 3° to 30° as well as being laser ready. A further beneficial option is the ability to retrofit existing PSM-1000s with a tilting head without the requirement of a factory return. Schematic diagram is located below.



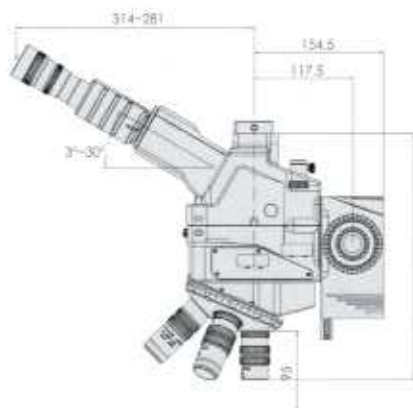
Stand/Stage

Equipping the PSM-1000 for simple and quick inspection, and/or laser work is achieved by opting for the stand/stage. The compact footprint allows for installation into space conscious work environments. The mechanical stage has a travel range of 75mm [X-axis] and 50mm [Y-axis].



PSM-1000 Tilting Head Dimensions

Unit : mm



PSM-1000 Applications



Failure analysis of wafers

Measuring microscope applications with addition of reticules



Digital documentation, analysis, and/or device testing

Modular Surface Inspection utilising parfocality adjustable objectives



Beam Splitter allows for Emission microscopy setup

Medical Research Applications with long working distance Plan Apochromat objectives

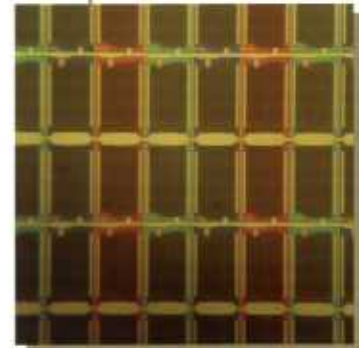
Polarisation with universal adaptable cassette sliders for device research



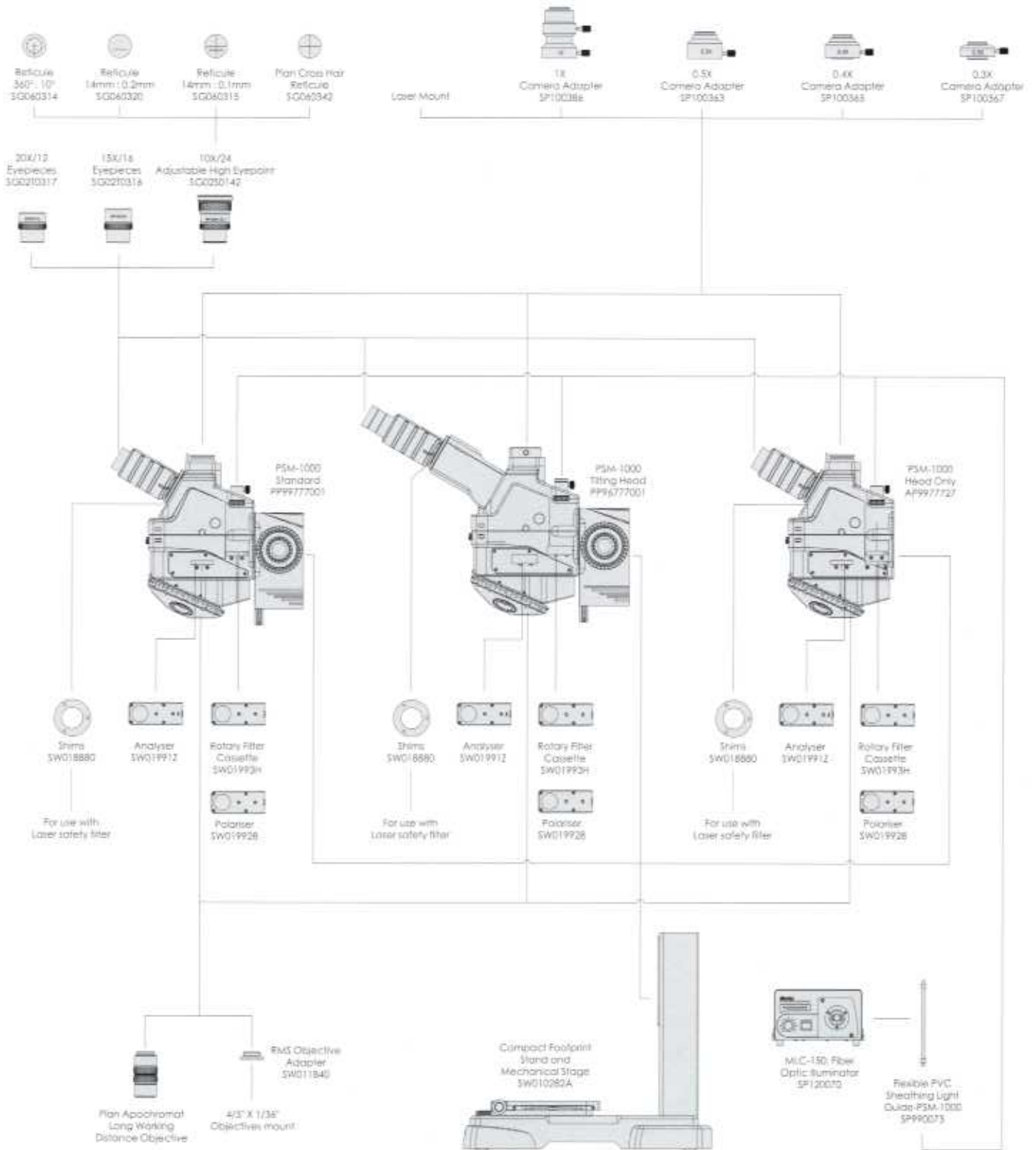
Engineer station for quick inspection



FPD laser repairs and laser machining



High magnification inspection



Motic® Microscopes

Motic

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Design Change: The manufacturer reserves the right to make changes in instrument design in accordance with scientific and mechanical progress, without notice and without obligation.

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Code No: SP010823D

Plan Apochromat Objectives

Extra And Ultra Long Working Distance



Extra Long Working Distance Objectives

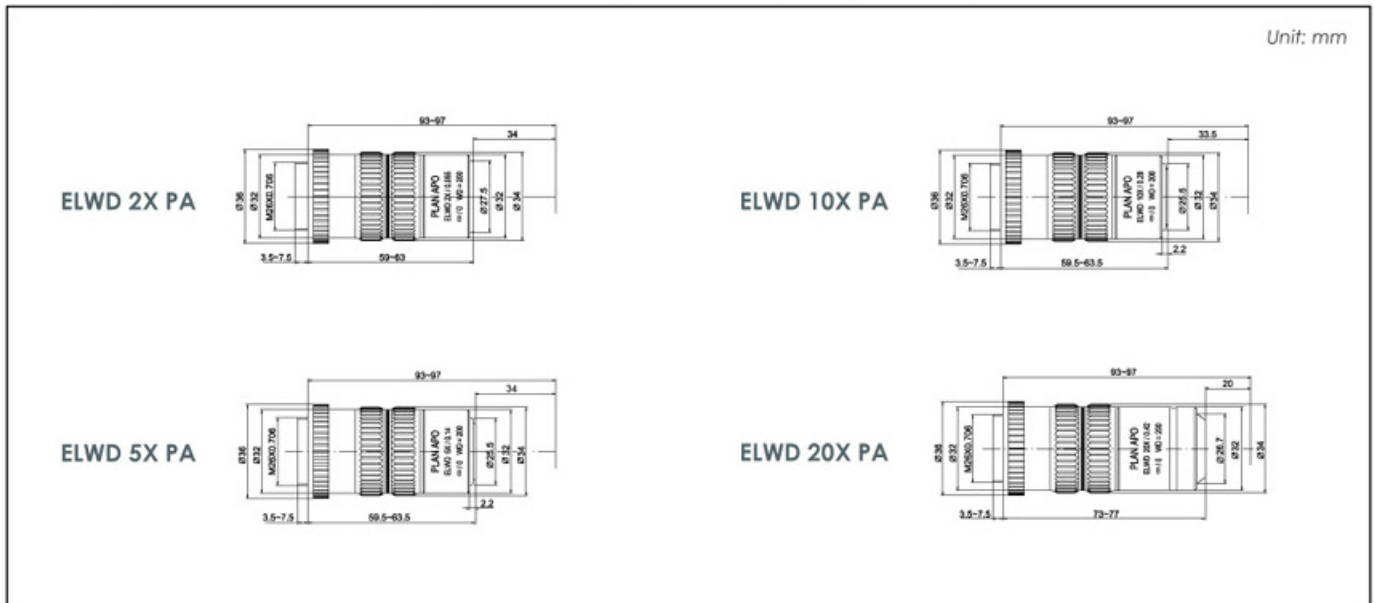
PARFOCALITY ADJUSTABLE PLAN APO ELWD PA

- The unique Motic feature of parfocality adjustability assures smooth transitions between magnifications as a convenient time saving function.
- The infinity corrected and strain-free optical system provides crisp and high contrast images at the numerical apertures and working distance demanded.



ELWD 20X PA
Parfocality Adjustable Objective

Schematic Diagrams of Plan Apochromat ELWD Objectives PA [Parfocality Adjustable]



Specifications Chart Plan Apochromat ELWD Objectives PA [Parfocality Adjustable]

Mag.	N.A	W.D (mm)	F (mm)	R (µm)	D.F (µm)	FOV (mm) (Ø24 eyepiece)	FOV (VxH,mm) (1/2" chip sensor)	FOV (VxH,mm) (2/3" chip sensor)	Weight (g)
ELWD 2X PA	0.055	34.0	100	5.0	91	Ø 12	2.4x3.2	3.3x4.4	270
ELWD 5X PA	0.140	34.0	40	2.0	14	Ø 4.8	0.96x1.28	1.32x1.76	260
ELWD 10X PA	0.280	33.5	20	1.0	3.5	Ø 2.4	0.48x0.64	0.66x0.88	270
ELWD 20X PA	0.420	20.0	10	0.7	1.6	Ø 1.2	0.24x0.32	0.33x0.44	320

Extra Long Working Distance Objectives

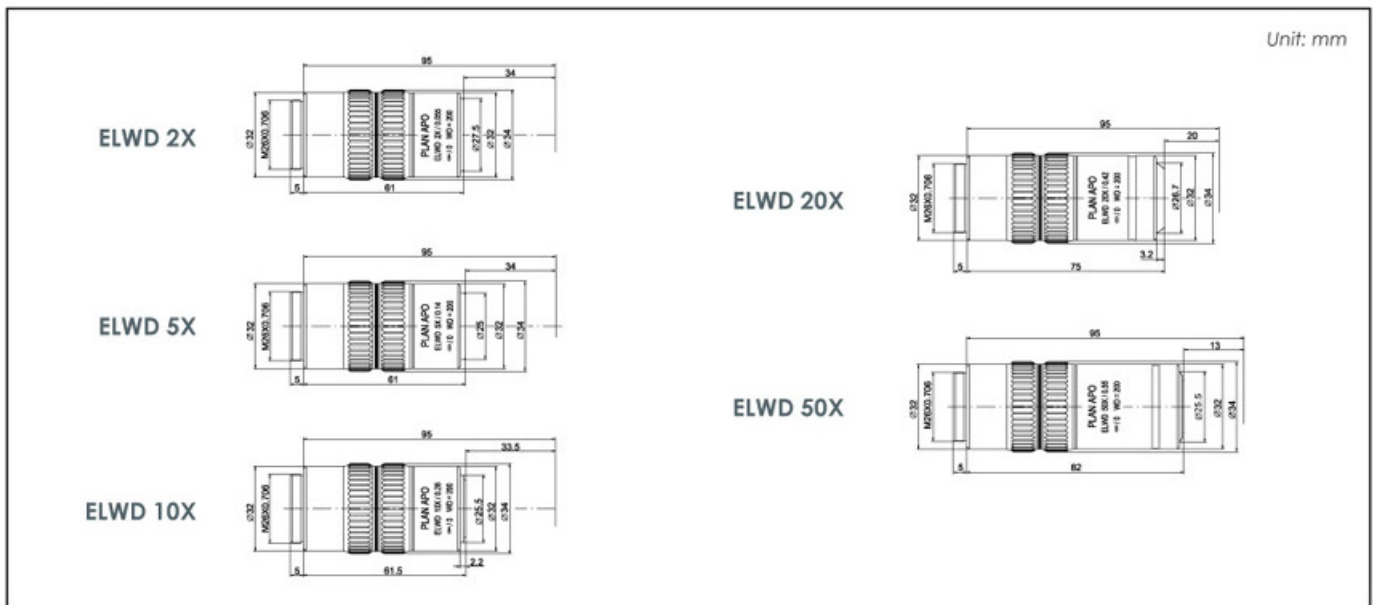
PLAN APO ELWD

- The infinity corrected and strain-free optical system provides crisp and high contrast images at the numerical apertures and working distance demanded.



ELWD 50X
Standard Objective

Schematic Diagrams of Plan Apochromat ELWD Objectives



Specifications Chart Plan Apochromat ELWD Objectives

Mag.	N.A	W.D (mm)	F (mm)	R (μm)	D.F (μm)	FOV (mm) (Ø24 eyepiece)	FOV (VxH,mm) (1/2" chip sensor)	FOV (VxH,mm) (2/3" chip sensor)	Weight (g)
ELWD 2X	0.055	34.0	100	5.0	91	Ø12	2.4x3.2	3.3x4.4	250
ELWD 5X	0.140	34.0	40	2.0	14	Ø 4.8	0.96x1.28	1.32x1.76	240
ELWD 10X	0.280	33.5	20	1.0	3.5	Ø 2.4	0.48x0.64	0.66x0.88	250
ELWD 20X	0.420	20.0	10	0.7	1.6	Ø 1.2	0.24x0.32	0.33x0.44	300
ELWD 50X	0.550	13.0	4	0.5	0.9	Ø 0.48	0.192x0.256	0.264x0.352	320

Extra Long Working Distance Objectives

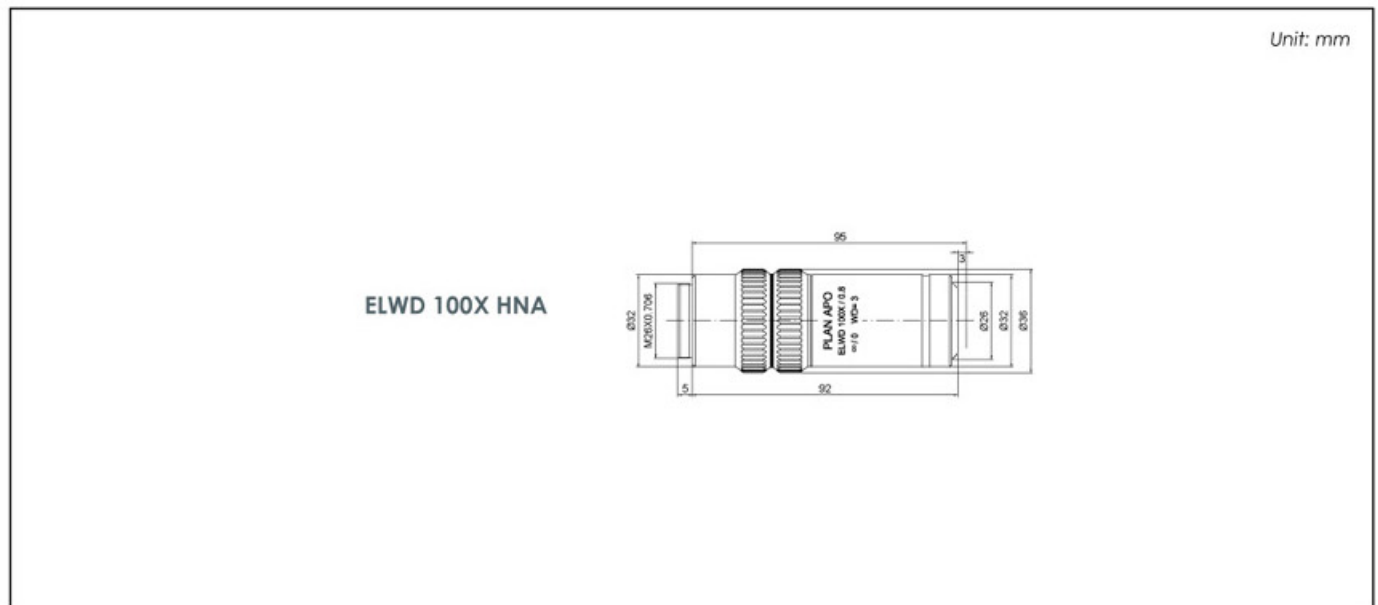
HIGH NUMERICAL APERTURE PLAN APO ELWD HNA

- Constructed for optimum resolution and image clarity, the high numerical aperture extra long Plan Apochromat objective is ideal for applications requiring both working distance and a high numerical aperture.
- The infinity corrected and strain-free optical system provides crisp and high contrast images at the working distance demanded.



ELWD 100X HNA
High Numerical Aperture Objective

Schematic Diagrams of Plan Apochromat ELWD Objective HNA [High Numerical Aperture]



Specifications Chart

Plan Apochromat ELWD Objective HNA [High Numerical Aperture]

Mag.	N.A	W.D (mm)	F (mm)	R (μm)	D.F (μm)	FOV (mm) (Ø24 eyepiece)	FOV (VxH,mm) (1/2" chip sensor)	FOV (VxH,mm) (2/3" chip sensor)	Weight (g)
ELWD 100X HNA	0.800	3.0	2.0	0.34	0.43	Ø 0.24	0.048x0.064	0.066x0.088	450

Ultra Long Working Distance Objectives

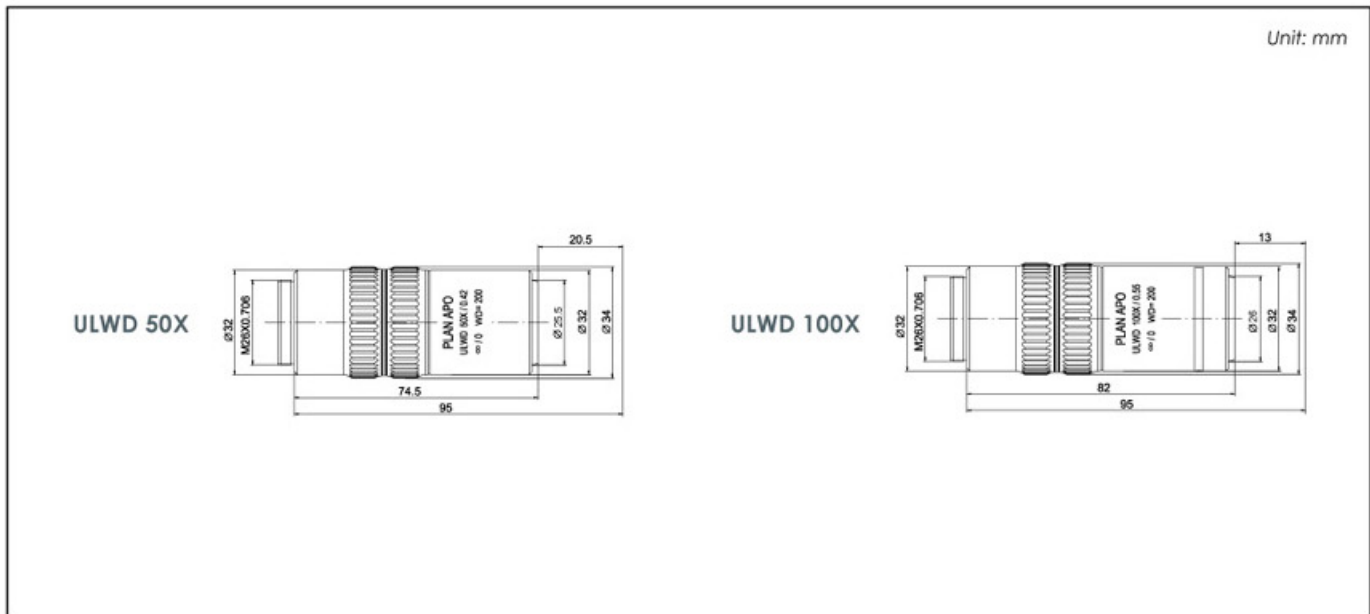
PLAN APO ULWD

- Corrected within the 24mm field of view for all optical aberrations throughout the visible spectrum, the ultra long Plan Apochromat objectives produce flat and true colour images with the extra amount of working distance demanded.



ULWD 100X
Ultra Long Objective

Schematic Diagrams of Plan Apochromat ULWD Objectives



Specifications Chart Plan Apochromat ULWD Objectives

Mag.	N.A	W.D (mm)	F (mm)	R (μm)	D.F (μm)	FOV (mm) (Ø24 eyepiece)	FOV (VxH,mm) (1/2" chip sensor)	FOV (VxH,mm) (2/3" chip sensor)	Weight (g)
ULWD 50X	0.420	20.5	4	0.7	1.6	Ø 0.48	0.10x0.13	0.132x0.176	300
ULWD 100X	0.550	13.0	2	0.5	0.9	Ø 0.24	0.05x0.06	0.066x0.088	340

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Motic®

More Than Microscopy

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